

Document Review Frequency	
3	Years

Review signatures on file with master copy of controlled document

LIGHT SOURCES DIRECTORATE REVISION LOG		
Document Number:		LS-ES-0002
Subject:		Procedure for the Acid Etching of Silicon and Germanium Crystals
Rev	Description	Date
1	Initial document	03/07/01
2	Updated safety requirements for working with HF	10/31/09
3	Removed room number 2-190 so that procedure could be used in 535 C-12	1/21/10
4	Included lab coat posting requirement when chemicals are being used.	5/24/11